

FAST - [resistor.wsp:1]

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0 1 2 3 4 5 6 7 8 9

☐ Drafts  
☐ Pending  
☒ Active

L1: (16980) trench\$2.clm.  
L2: (9115) 1 and etch\$3.clm.  
L3: (4021) 2 and (gate.clm. or contact.clm.)  
L4: (1750) 3 and ((contact near5 opening) or interconnect or plug)  
L5: (1601) 4 and (mask or resist or photoresist)  
L6: (1519) 5 and contact  
L7: (1079) 6 and (fill\$3 near9 (opening or hole or trench))  
L8: (576) 7 and (contact adj2 (hole or opening))  
L9: (455) 8 and gate  
L10: (274) 9 and (plug.clm. or (contact adj opening).clm. or (contact ac  
L11: (206) 10 and gate.clm.  
L12: (118) 11 and (self adj align\$2)

☐ Failed  
☒ Saved

(0) ("(thinadjfilm)nearresistor").PN.  
(0) ("(thinadjfilm)nearresistor").PN.  
(150130) thin adj film  
(14957) (thin adj film) and resistor  
(2054) ((thin adj film) and resistor) and ((thin adj film) near resistor)

11 and (self adj align\$2)

	U	I	P	T	P	Document ID	Issue Dat	Pages	Title	Current OP	Current XR	Retrieval	Inventor	S	C	J	M
60	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6635566	20031021	12	Method of making	438/638	257/E21.25		Blosse, Alain et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
61	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6617216	20030909	27	Quasi-damascene gate, self-aligned source/dra	438/296	438/303; 438/595		Hu, Hung-Kwai	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
62	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6605542	20030812	56	Manufacturing method of semiconductor devices b	438/700	257/E21.25		Seta, Shoji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
63	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6596648	20030722	83	Material removal method for forming a structure	438/745	257/E21.01		Wu, Zhiqiang et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
64	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6548394	20030415	22	Method of forming contact plugs	438/618	257/296; 257/906		Peng, Hain-Tang et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
65	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6475906	20021105	13	Gate contact etch sequence and plasma doo	438/637	257/E21.50		Lee, Brian	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
66	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6472266	20021029	17	Method to reduce bit line capacitance in cub	438/241	257/300; 257/E21.65		Yu, Chih-Hsing et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
67	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6465298	20021015	24	Method of fabricating a semiconductor-on-insula	438/242	257/E21.65		Forbes, Leonard et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
68	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6461967	20021008	88	Material removal method for forming a structure	438/705	216/38; 216/87		Wu, Zhiqiang et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
69	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6461911	20021008	24	Semiconductor memory device and fabricating	438/253	257/298; 257/308		Ahn, Tae-hyuk et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
70	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6432816	20020813	10	Method for fabricating semiconductor device	438/637	438/299		Kim, Jeong Ho et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
71	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6399512	20020604	12	Method of making	438/723	216/38;		Blosse, Alain et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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Ready